IFW

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Tsao, Yi-Chang; et al.

Serial No.: 10/607,607

Filed: June 27, 2003

For: "APPARATUS AND METHOD FOR

Description: Examiner: Gabor, Otilia

Our Ref: B-5136 621042-5

Date: June 9, 2005

INSPECTING CRYSTAL QUALITY OF)

A POLYSILICON FILM") Re: Amendment and Response

AMENDMENT AND RESPONSE

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

JUN 1 3 2005

This is in reply to the non-final Office Action mailed on March 10, 2005, an initial response to which is due no later than

June 10, 2005.

Please amend the above-identified application as described below and consider the following remarks. All amendments and remarks herein are made without prejudice.

Amendments to the Specification begin on page 2 of this paper.

Remarks/Arguments begin on page 3 of this paper.